



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/660,709 Confirmation No. 7653  
Applicant : Y. KAWAMURA et al  
Filed : September 12, 2003  
Title : METHOD FOR POLISHING SURFACE OF  
SEMICONDUCTOR DEVICE SUBSTRATE  
TC/AU : 1763  
Examiner : G.A. Goudreau  
Docket No. : ASA-955-02  
Customer No.: 24956

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Sir:

In response to the Office Action of October 7, 2005, please amend the above-identified application as follows. A Petition and fee for a three-month Extension of Time also accompanies this response.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks / Arguments** begin on page 9 of this paper.